



Appl. No. 09/291,538

Amtd Dated September 10, 2003

Reply to Office Action of March 10, 2003

Attorney Docket No. 005586/D8326 (81784.0208)

Customer No. 26021

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9/26/03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Hidenori OGATA et al.

Serial No: 09/291,538

Confirmation No.: 2245

Filed: April 14, 1999

For: LASER ANNEAL METHOD OF A
SEMICONDUCTOR LAYER

Art Unit: 2822

Examiner: M.A. Wilczewski

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Date

AMENDMENT

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In conjunction with the filing of the accompany Request For Continued Examination (RCE), and in response to the final Office Action of March 10, 2003, the period for response to which is being extended by 3-months to September 10, 2003 by the accompanying petition, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the Listing of Claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.

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